



Atty. Dkt. No. 039262-0150

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Tadahiro OHMI et al.

Title: VACUUM PROCESSING APPARATUS AND VAPOR DEPOSITION APPARATUS

Appl. No.: 10/568,706

International 8/19/2004

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Examiner: Keath T. Chen

Art Unit: 1792

Confirmation 4847

Number:

AMENDMENT ACCOMPANYING RCE

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This communication is responsive to the Final Office Action dated July 24, 2008, concerning the above-referenced patent application.

Applicants have included with this amendment the payment for a three-month extension of time to make this response timely.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this document.

Remarks/Arguments begin on page 5 of this document.

Please amend the application as follows: